Svnos

HIGH POWER LASER BEAM PROFILER / NFP MEASUREMENT & ANALYSIS OF HIGH POWER LASER

SOPHISTICATED OPTICAL BEAM NFP MEASUREMENT OPTICS FOR HIGH POWER LASER M-Scope type HS Optical beam profile measurement optics, customized especially for output ~10W class high power laser.

M-Scope type HS is optics for beam profile measurement of output ~10W class high power lasers. After passing through the objective lens, the luminous flux from sample is 99.99% attenuated by two-stage beam sampler, and imaged on the detector.

[Features]

OAttenuation of incident beam with two-stage beam sampler and ND filters OVarious objective lens can be selected (M-Plan Apo NUV/NIR series objective lens) OHigh-performance NFP measurement system can be constructed by using Synos' optical beam analysis module AP013 together.

【Optics selection】 * Plea ○for 850-940nm ○for 400-450nm	se contact us regarding the measurement wavelength. M-Scope type HS/NIR M-Scope type HS/BL
[Summary of specification]	
OMeasurement method:	dedicated optics & image processing
OAttenuation method:	Approx. 99.99% attenuated by two-stage beam sampler, and ND filter (combined)
OPolarization dependent	compensation: Compensated by 2-stage
	orthogonal arrangement of attenuation
	mirrors in beam sampler
○Target input power:	Approx. ~10W

C mount

Objective lens: M-Plan Apo NUV, M-Plan Apo NIR Objective lens change: By manual revolver OIntermediate lens: $1 \times$ OEpi-illumination: Option

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OCamera mount

[Standard component]

OMain optics:

Optics base:

Available detector]

Hi-resolution CMOS detector ISA071/ISA071GL

Option]

Option for M-Scope type HS optics

• 2× intermediate lens port MS-OP016-RL2

- Intermediate lens unit that doubles the overall magnification of the optical system. (up to 200× with 100× objective lens)
- 1/2× intermediate lens port MS-OP016-RLH Intermediate lens unit that halves the overall magnification of the optical system.
- Coaxial epi-illumination port MS-OP016-CEP
- Coaxial epi-illumination port with removable half mirror.
- Dummy filters MS-OP016-DF

wedge type dummy filters for pulse/low power measurement OAccessories for optics

• Objective lens, ND filter, coaxial epi-illumination light source, optics bench, etc.

M-Scope type HL HIGH POWER LASER NFP MEASUREMENT OPTICS

Optical beam profile measurement optics, customized especially for high power laser.

M-Scope type HL is optimized especially for optical beam profile measurement of high power laser. Approximately 5% of the optical beam emitted from sample is reflected by beam sampler which is installed in front of objective lens. Reflected beam is introduced to imaging detector through NFP optics.

[Features]

OAttenuation of incident beam with beam sampler before objective lens, and ND filter OHigh-performance NFP measurement system can be constructed by using Synos' optical beam analysis module AP013 together.

Optical magnification is maximum 20x (option, 10x objective lens and 2x intermediate lens.) [Summary of specification]

OMeasurement method:dedicated optics & image processing

OAttenuation method: Approx. 95% attenuated by beam sampler, [Available detector] and ND filter (combined)

OMeasurement wavelength:Select one wavelength from the range of 400 nm to 1100 nm

- \bigcirc Target input power: Approx. $\sim 10W$
- Objective lens: M-plan 10x/N.A.0.28
- OIntermediate lens: $1 \times$
- \bigcirc Field of view: Approx. 706×529µm
- OPixels resolution: Approx. 0.345µm

* The value of field of view and pixel resolution is approximate value when using Hi-resolution CMOS detector ISA071/ISA071GL.

OEpi-illumination: Option OCamera mount: C mount

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[Standard component]

OMain optics: 1

Optics base:





OHi-resolution CMOS detector ISA071/ISA071GL

[Ontion]

Option for M-Scope type HL optics

- •2× intermediate lens port MS-OP011-RL2 Intermediate lens unit that doubles the overall magnification of the optical system. (up to 20× with 10× objective lens)
- •1/2× intermediate lens port MS-OP011-RLH Intermediate lens unit that halves the overall magnification of the optical system.
- Coaxial epi-illumination port MS-OP011-CEP Coaxial epi-illumination port with removable half mirror.
- OAccessories for optics
 - Objective lens, ND filter, coaxial epi-illumination light source, optics bench, etc.

Technical information [Simple structure of M-Scope type HS]

The light flux emitted from the sample is attenuated to approximately 99.99% by two beam samplers installed in the latter stage of the objective lens. The beam reflected by the beam sampler is absorbed by the beam damper installed in the optical system. The beam that has passed through the beam sampler is further attenuated to an appropriate amount by ND filter and then introduced to image detector for image processing analysis.

